

Docket No.: 1514.1032

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE EXPEDITED PROCEDURE PURSUANT TO 37 CFR §1.116 REQUESTED

Attn: Mail Stop AF

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In re the Application of:

Enter

Ji Yong PARK et al.

MS

Serial No. 10/690,507

Group Art Unit: 1722

3/14/07

Confirmation No. 6043

Filed: October 23, 2003

Examiner: Song, Matthew J.

For:

METHOD FOR MANUFACTURING POLYCRYSTALLINE SILICON THIN FILM AND THIN FILM TRANSISTOR FABRICATED USING POLYCRYSTALLINE SILICON THIN

FILM MANUFACTURED BY THE MANUFACTURING METHOD

AMENDMENT AFTER FINAL

Commissioner for Patents PO Box 1450 Alexandria, VA 22313-1450 February 28, 2007

Sir:

This is in response to the Office Action mailed November 1, 2006, and having a period for response set to expire on February 1, 2007.

The following amendments and remarks are respectfully submitted. Reconsideration of the claims is respectfully requested.

03/01/2007 JADDO1

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